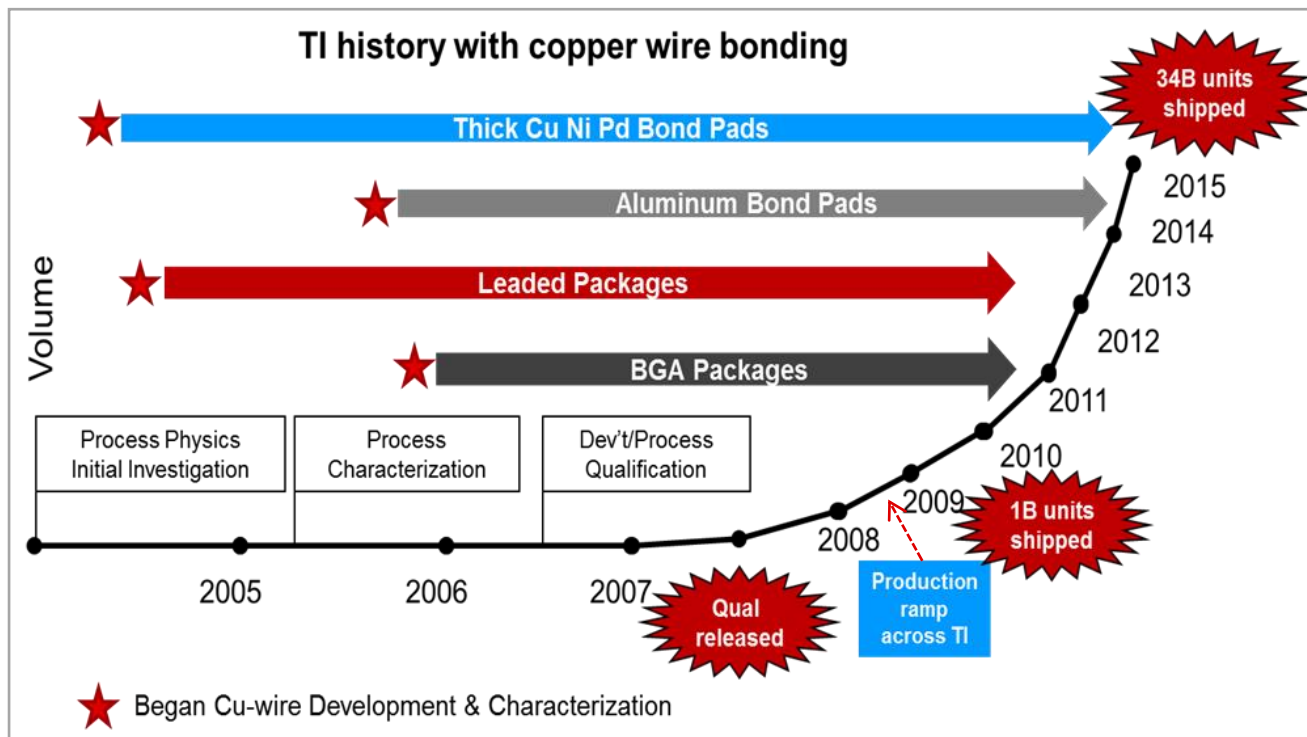


# Cu Wirebond in PEMs:

**Mukul Saran, Ph.D.**  
**Texas Instruments Inc**  
**Dallas, TX**

# Looking Backwards to Now:



## Applications:

- Commercial
- Telecom
- Industrial
- Automotive (safety, powertrain, Infotainment etc)

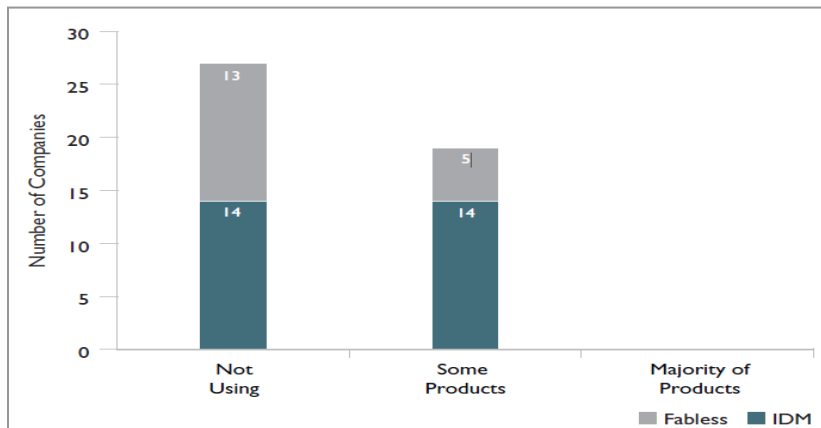
## Packages:

All (QFN, QFP, PDIP, SOIC, TSSOP, BGA & others)

**AT sites:** > 14  
(internal & external)

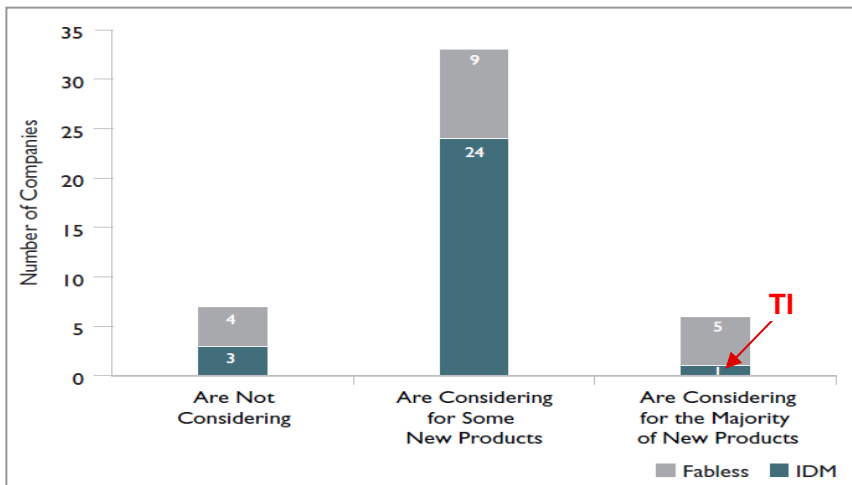
# Rewind to 2010 - Industry Trends Then

## Use in Current Products



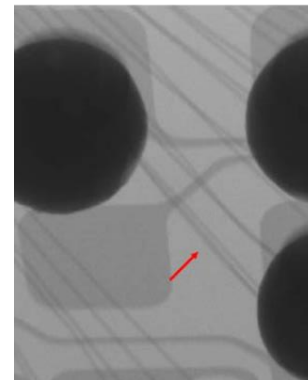
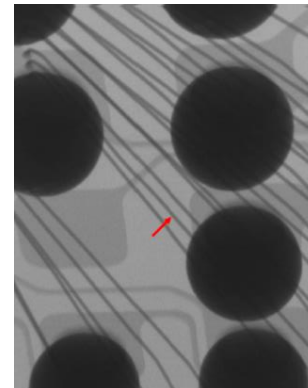
- Limited use in the global SC Industry, but growing.
- TI was leading the charge in conversion to Cu w/b.

## Planned Use over Next 3 yrs



# Talking About Cu

- What drove us to Cu?
- How Reliable is it?
  - Very Reliable, but....*
  - Temperature - Robust*
  - Temperature-Cycling – Some differences from Au-wire*
  - Humidity, Bias and Temperature – Requires more attention than Au-wire*
- What Have we Learned
  - Development and Qualification:*
  - Maintaining Quality & Reliability in Production:*
- HiRel Concerns
- Summary



# Reasons to Choose Cu

Property	Au Wire	Cu Wire	PCC Wire
FAB Hardness (HV)	60	85-95	80-95 w/gradient
Bond Hardness (HV)	80	128	unknown
Modulus (GPa)	75-100	80-90	80-90 inside 121 outside
CTE (ppm/K)	14.2	16.5	16.5 inside 11.5 outside
Resistivity ( $\mu\Omega\text{-cm}$ )	2.3	1.7	1.7 inside 1.1 outside
Corrosion Potential (V, SHE)	1.498	0.521	0.987 outside 0.521 inside
Fatigue Resistance	Good even if Delaminated	Good if not delaminated	Unknown
Constituent Distribution	N/A	N/A	Critical, Pd must be on outer FAB

## Motivation for Cu

- + **Lower Material Cost**
- + Lower resistivity
- + Higher thermal conductivity
- + Resistant to Kirkendall voids
- + Longer high-temperature storage (HTS) life

=> So, how reliable is Copper?

# How Reliable Is Cu?

=> It can be very reliable well beyond Jedec stress guidelines

# Cu-WB Reliability Stress Performance

## Reliability Performance

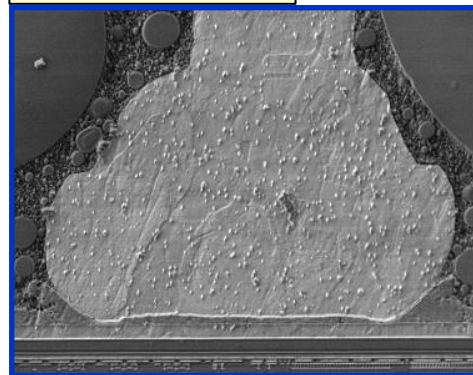
Reliability Stress	Condition	Minimum Required Duration	Duration Passed
Unbias HAST	130C/85%RH	96	504
	110C/85%RH	264	792
BHAST	110C/85%RH	264	792
Temp Humidity Bias	85C/85%RH	1000	1000*
Hi Temp Oper Life	125C	1000	1000
High Temp Storage	150C	1000	2000
Temperature Cycle	-55/125C	700	4000
Thermal Shock	-55/125C	None	2000

\* No package defects found

## Bond-Shear

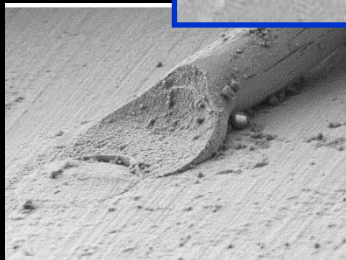
	Shear (g)				Ball X			Ball Y			Shear/Unit Area (mg/um2)		
Unit	Lot 1	Lot 2	Lot 3	Au Control	Lot 1	Lot 2	Lot 3	Lot 1	Lot 2	Lot 3	Lot 1	Lot 2	Lot 3
1	18.85	17.54	17.68	17.68	45.30	42.70	44.52	44.40	45.91	46.28	11.93	11.37	10.92
2	18.85	17.20	17.68	17.68	44.52	43.27	42.72	46.28	45.68	47.10	11.64	11.07	11.16
3	18.67	17.21	18.03	18.03	42.72		42.49	47.10		46.74	11.78		11.53
4	17.81	18.00	17.34	17.34	42.09		45.40	46.74		45.88	11.49		10.60
5	18.44	16.41	18.02	18.02	45.71		43.24	44.63		45.91	11.50		11.55

## uHAST 672 HRS

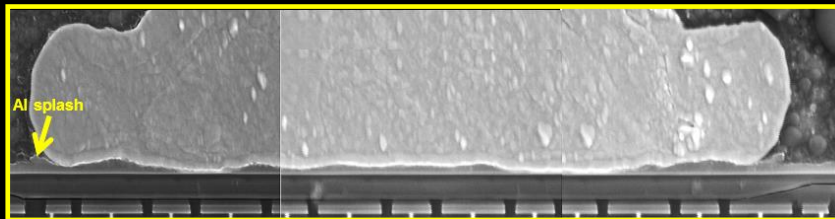
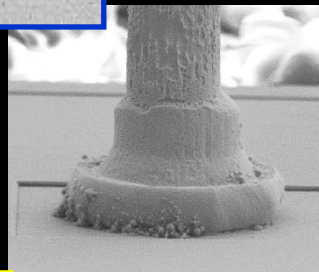


=> Cu-wirebond can demonstrate superior reliability performance in plastic packages

# Cu-Wirebond (Post-500TC)



Both Stitch- and Ball-bond remain intact after 500 Temperature Cycles Between -65C/150C. Molded QFN





# The Basics of Cu-Al IMC

- We know more, now that we can image the IMC using a SEM

# IMC Formation – Phase Diagram

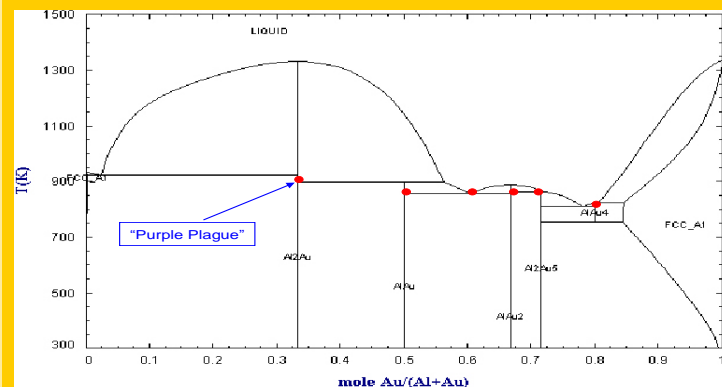
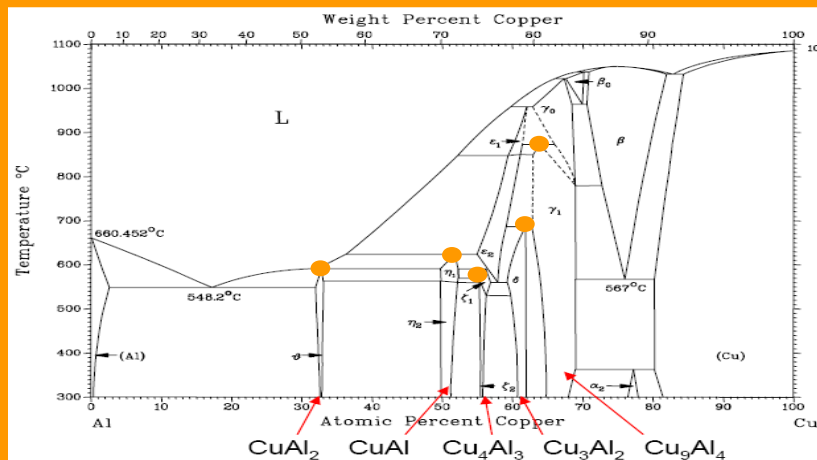
**AuAl<sub>2</sub>** – Purple plague (Al wires on Au pads)

**AuAl**

**Au<sub>2</sub>Al**

**Au<sub>5</sub>Al<sub>2</sub>** – Grows adjacent to Al-pads

**Au<sub>4</sub>Al** – Adjacent to the ball. Can grow at the expense of Au<sub>5</sub>Al<sub>2</sub> during HTS. Susceptible to oxidation and corrosion by mold-compd epoxies



**CuAl<sub>2</sub>**

**CuAl**

**Cu<sub>4</sub>Al<sub>3</sub>**

**Cu<sub>3</sub>Al<sub>2</sub>**

**Cu<sub>9</sub>Al<sub>4</sub>**

White-Yellow

Grey

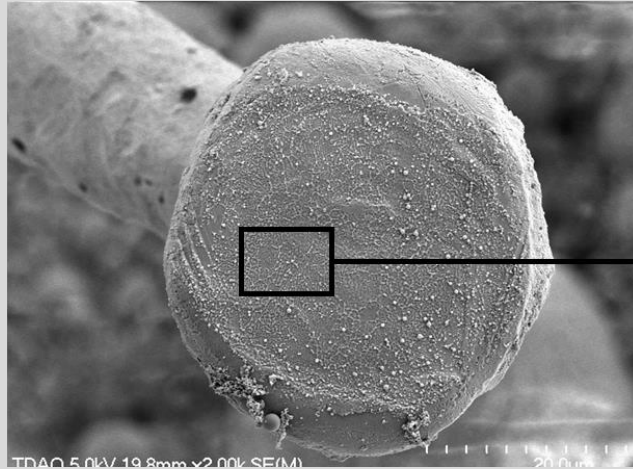
White--yellow

Adjacent to Cu-ball

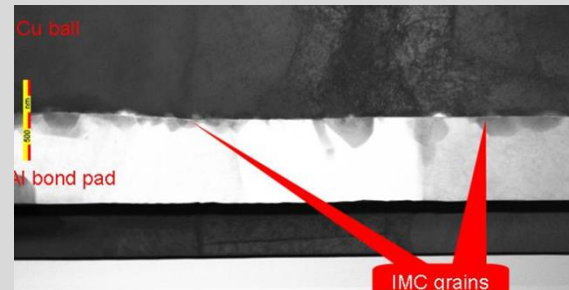
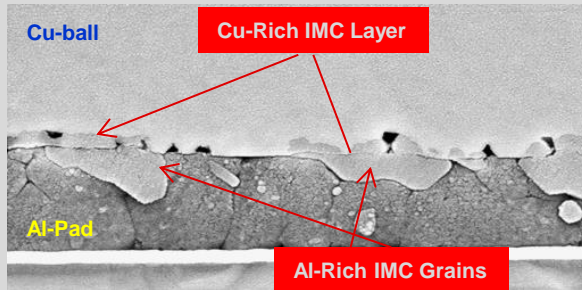
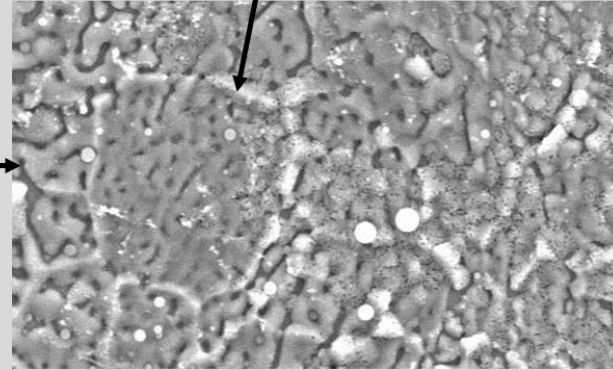
At shorter storage times <200hr, a grey phase is dominant. At longer times, yellow phases are seen.

Phase determination is difficult in as-bonded samples due to very thin layers. The above results were obtained after 250C storage. The results may be different at lower temperatures.

# The Basics



IMC ring at Al grain-boundary

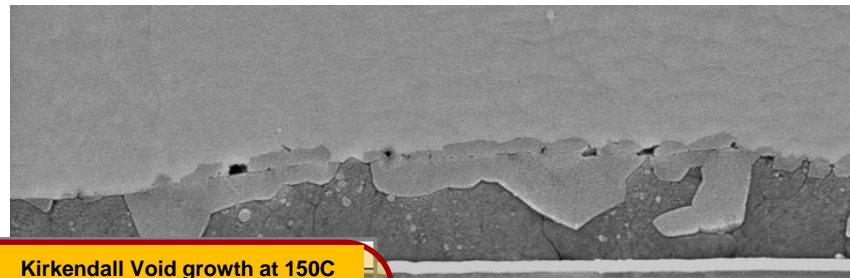
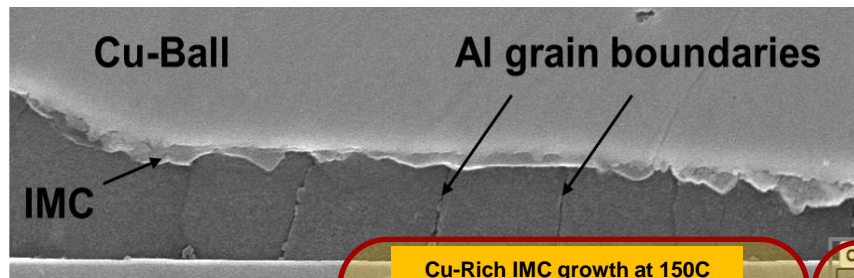


Ref: Copeland & Saran,, Copper to Aluminum bonding: IMC Characterization through New Mechanical Sectioning Methods, Proc 36th International Symposium for Testing and Failure Analysis, ISTFA 2010

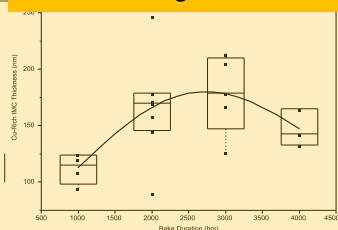
# Stable against Kirkendall Voiding

As-molded

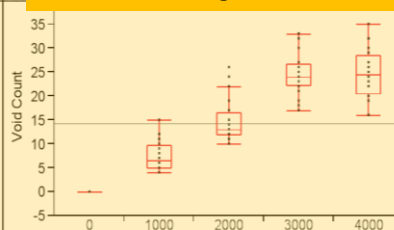
2000hrs HTSL



Cu-Rich IMC growth at 150C

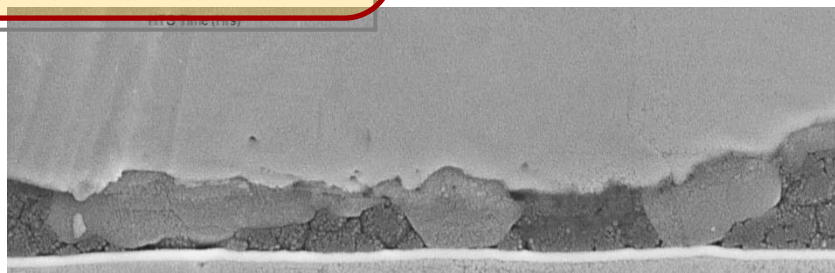
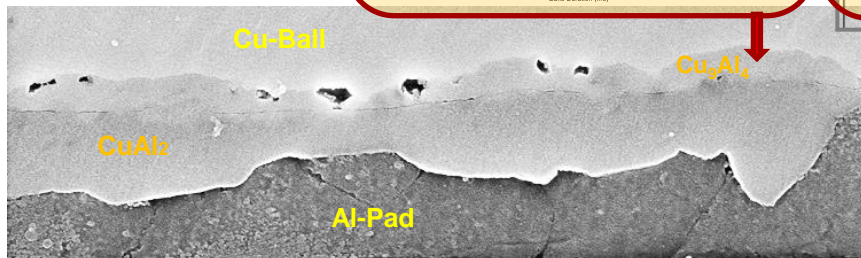


Kirkendall Void growth at 150C



3000hrs HTSL

4000hrs HTSL



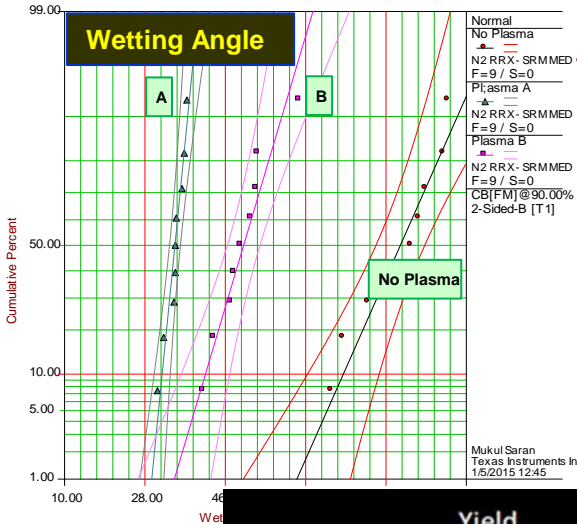
# What Have We Learnt?

**Knowledge is Power!**

**We have learnt a lot over the years!**

# Bond-Surface Cleanliness

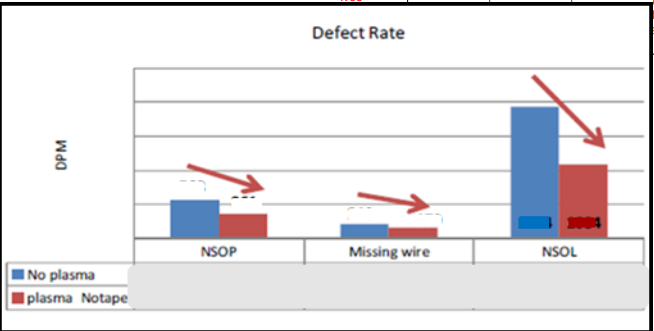
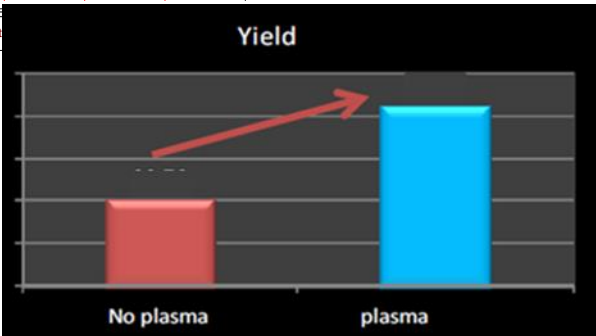
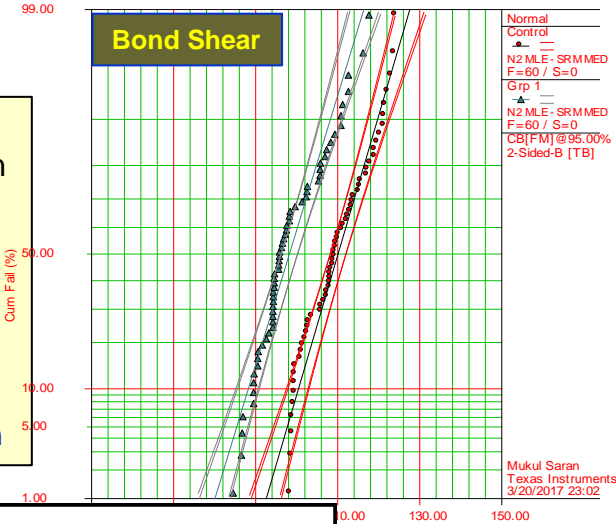
## Plasma Treatments



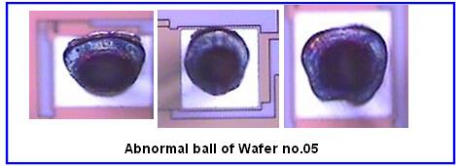

$\mu1=85.2222$ ,  $\sigma1=9.9673$ ,  $\rho=0.9568$   
 $\mu2=34.7333$ ,  $\sigma2=2.2314$ ,  $\rho=0.9606$   
 $\mu3=50.1111$ ,  $\sigma3=6.6684$ ,  $\rho=0.9688$

**Conclusions:**

- Plasma reduces the wetting angle on bonding surface
- Longer Power/exposure (A vs B) improves wetting angle
- Benefits yield, NSOL and NSOP
- Bond-shear strength increases
- **Surface cleanliness more critical than Au due to limited IMC growth**



# Sensitivity To Si Bond-Pad Stack

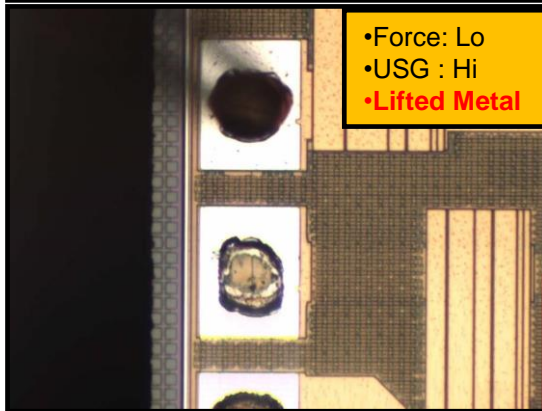
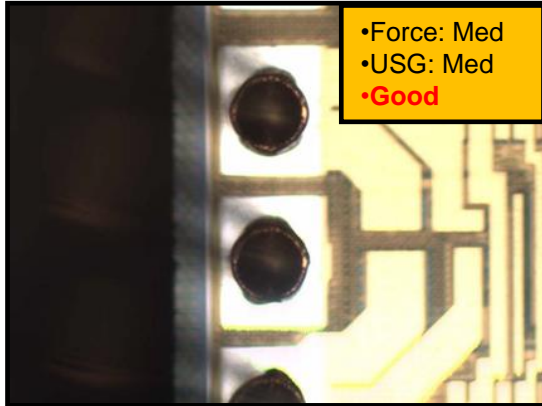
	Al-0.5%Cu	Al-2%Cu
Low-K Dielec Sandwich + Pad Reinforcement	Abnormal	 Abnormal
Oxide/SOG Sandwich + No Pad Reinforcement	 Abnormal	<p><b>** Bond Parameters Optimized For This Stack up **</b></p> <p><b>High Bond-Parameters (force/power) were used</b> <b>Used the same set on all other stack-ups</b></p> Normal

- Changing underlying bond-pad structure impacts Wirebond outcomes.

=> Bonding recipes may require optimization for different bond-pad metallizations



# Bond-Pad Damage

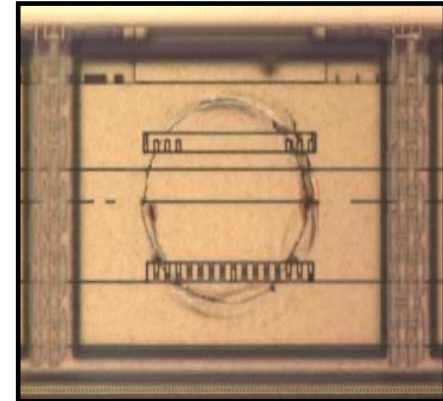
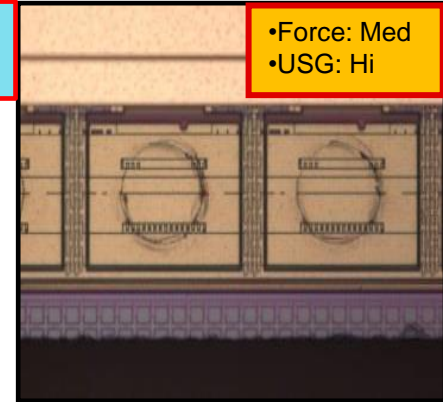


Lifted Metal @  
Bond and/or at  
Wirepull

Lower bond parameter range than  
Au, for damage-free bonding

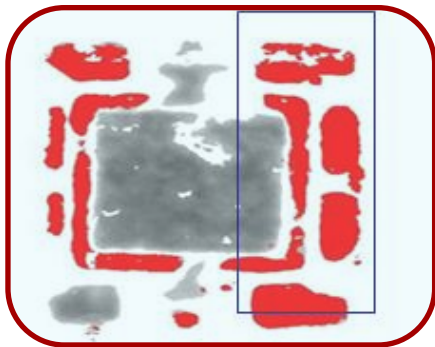
Post-assembly or reliability fails due  
to Lifted Metal or Crater crack  
growth during Temperature Cycling

Under-pad  
Damage



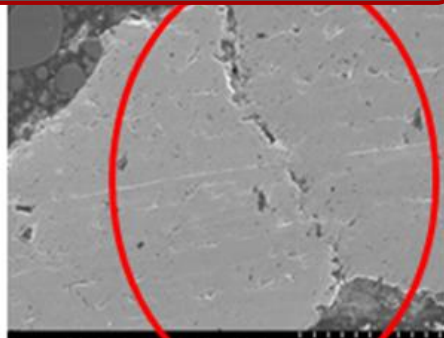
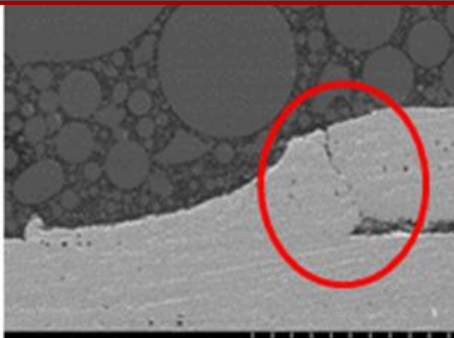
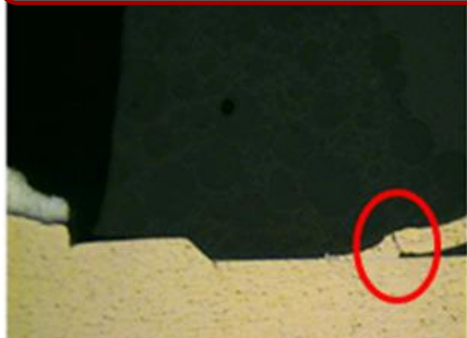


# Dangers with Delamination – Stitch Cracks

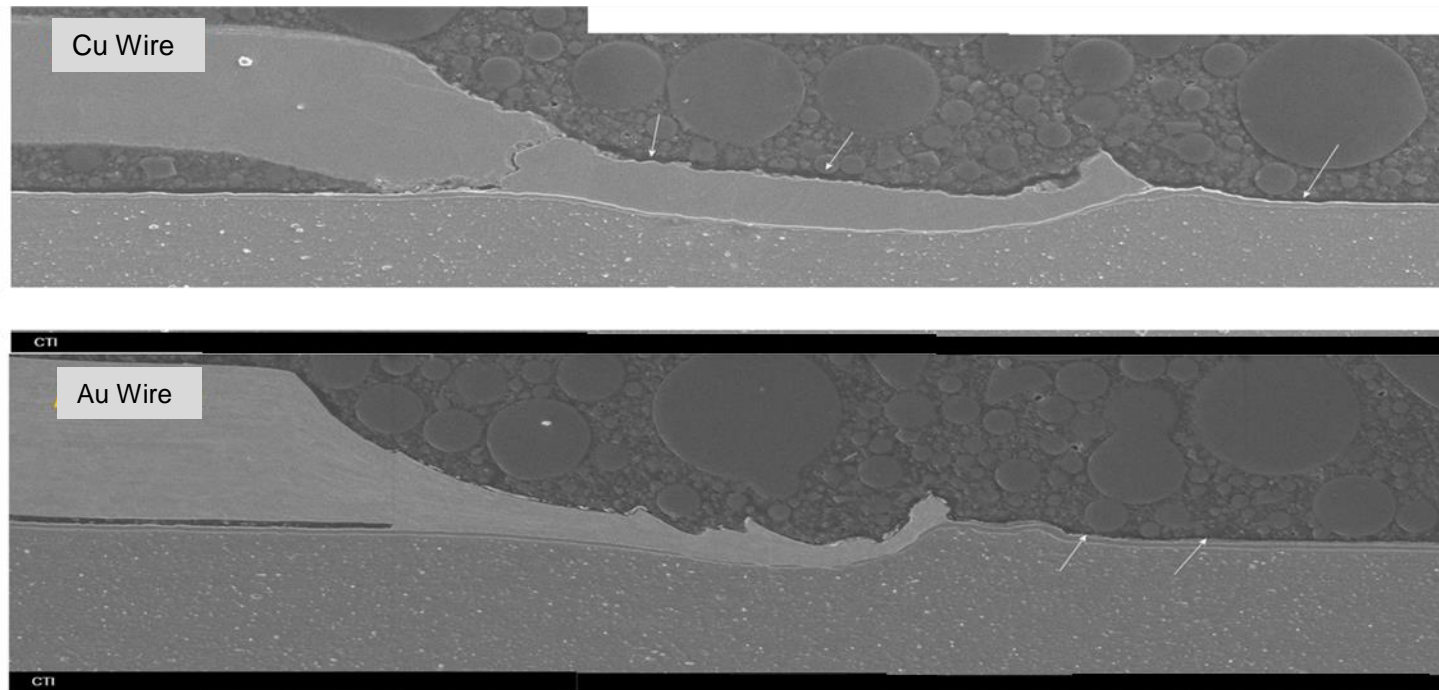


CSAM images show delamination after pre-conditioning in the die attach-pad areas, as well as on leadfinger areas

Mold-compound delamination can result in stitch-fracture during Temperature Cycling due to thermo-mechanical fatigue. Copper undergoes work hardening during stitch formation process.



# Mold-Delamination and Stitch Crack

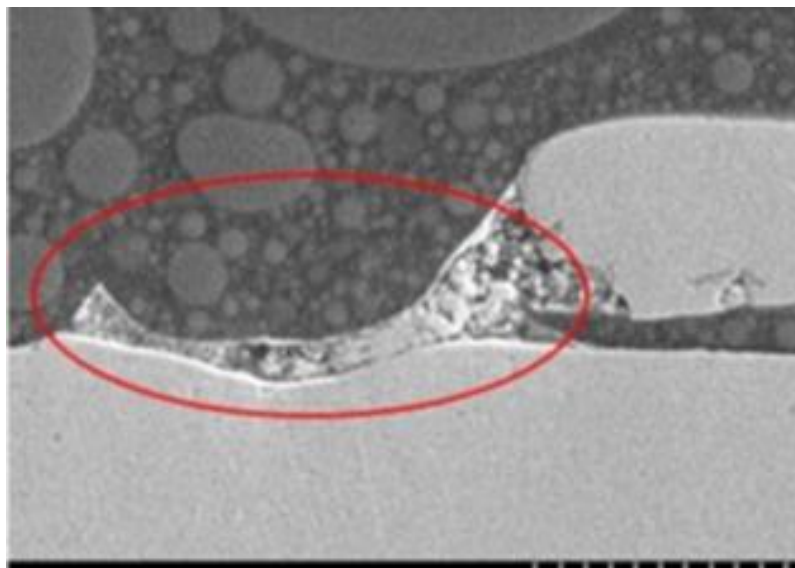


Cu Wire –vs- Au Wire Stitch After **1000 T/C**; Au Wire Had No Damage. Both have delamination t0 and after 1000 T/C. Arrows indicate mold-compound delamination

# Dangers with Delamination: Stitch Corrosion

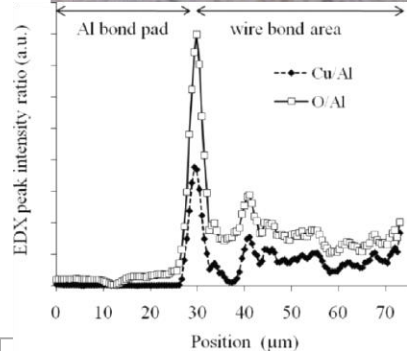
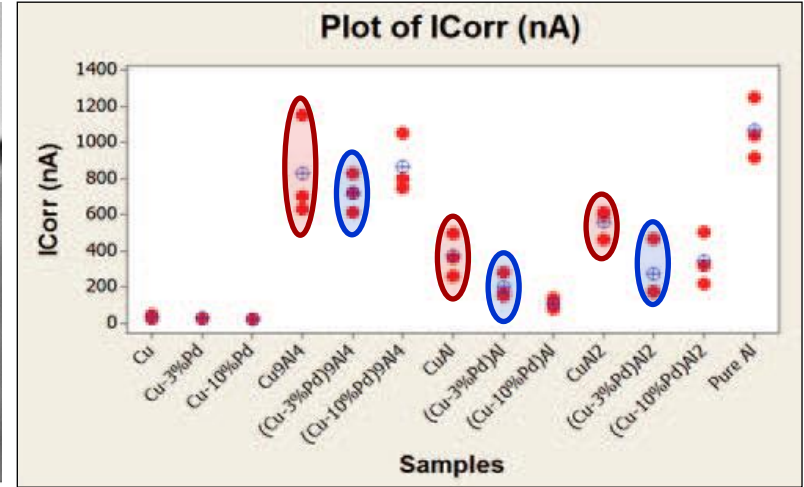
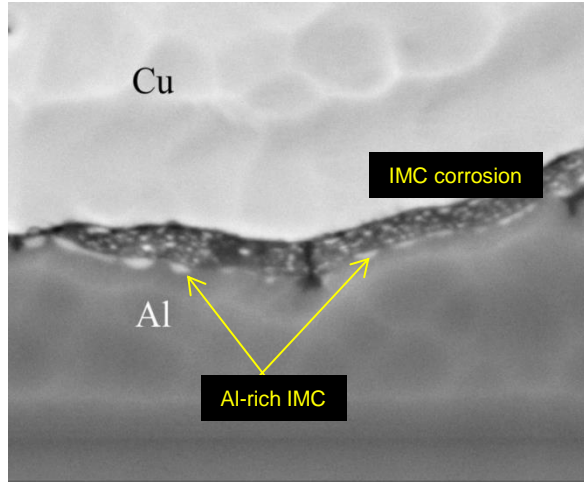
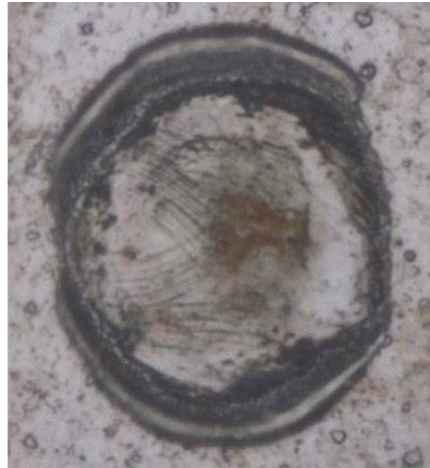


- *How did the corrosion happen inside?*
  - Delaminations reduce product robustness
  - Au-wire does not corrode



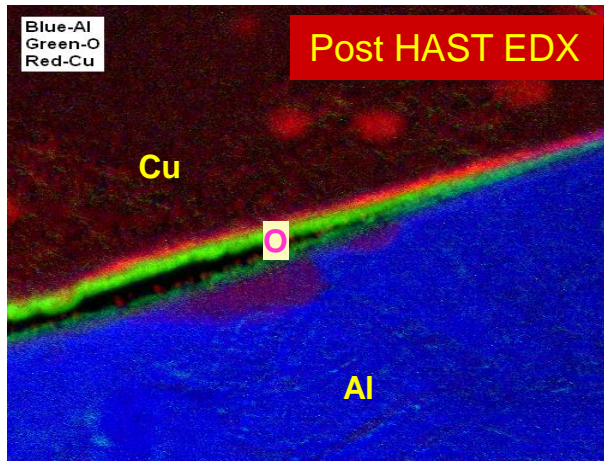
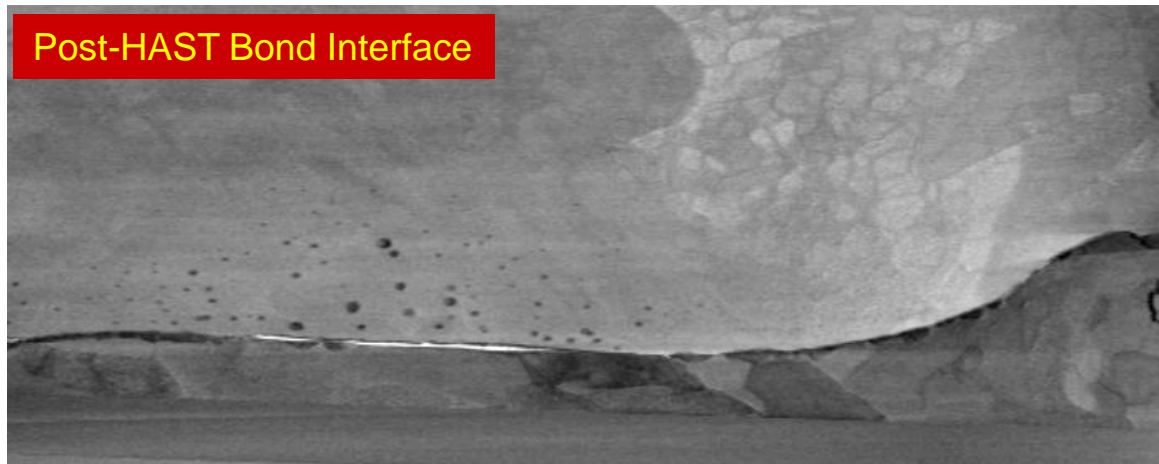
- Initially strong bonds can fail this way
- *Robustness demands package integrity* at 'Time-zero' and under stress

# Corrosion of Cu-Al Bonds



- Cu<sub>9</sub>Al<sub>4</sub> is the most susceptible to corrosion
- Addition of Pd in Cu IMC slightly improves the corrosion resistance

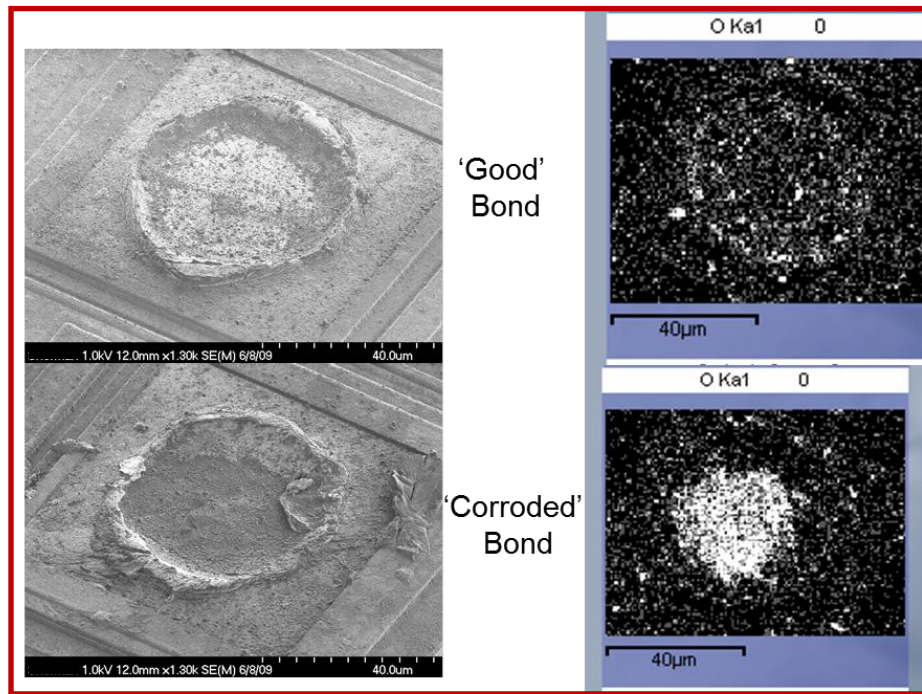
# Corrosion of Cu-Al Bonds



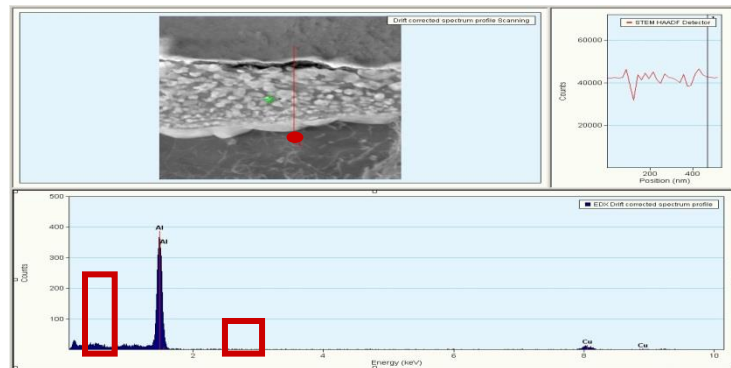
- Cu bond interface corrodes by oxidation of the Cu/Al interface.
- Separation occurs in the oxidized IMC layer towards the interface with Al
- Separation can occur even in regions which may have previously grown an IMC.
- A well-formed bond with high bond-strength can fail easily due to corrosion



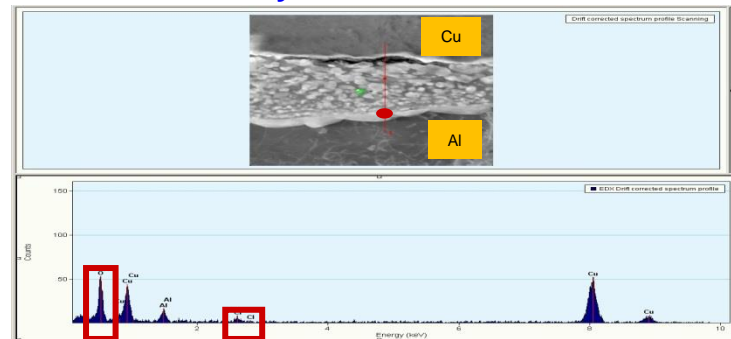
# Cu-Al IMC Corrosion - Chlorine



No O or Cl in Aluminum just below the interface.



Cl & O in layer between Al & Cu.

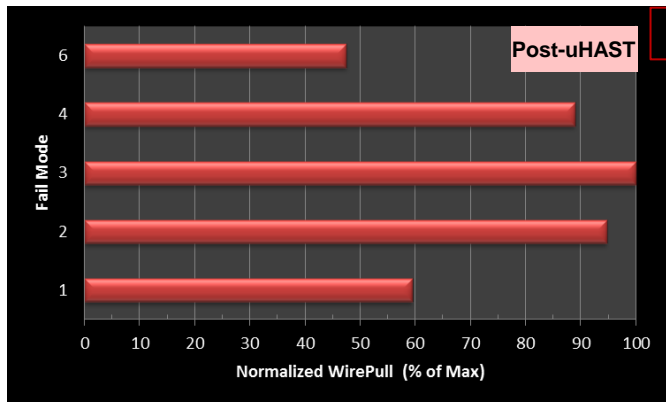


# Mold-Compounds: Role in Cu Corrosion

Supplier	Mold-Compd	Autoclave (121C, 100%RH, 2atm)	ub_HAST (110C / 85% RH)	ub_HAST (130C / 85% RH)	Biased HAST (130C/85% RH)	THB (85C/85% RH)
		-	Passed	-	-	Passed
		-	Passed	-	-	Passed
		-	Passed	-	-	Passed
		-	Passed	-	-	Passed
		-	Passed	-	-	Passed
		-	Passed	Passed	Passed	Passed
		Passed	-	-	In Qual	-
		Passed	-	Passed	-	In Qual
		Passed	-	-	Passed	-
		Passed	-	-	Passed	-
		No Plan	No Plan	No Plan	No Plan	No Plan
		Passed	-	-	No Plan	-
		Passed	-	-	Passed	-
		Passed	-	-	Passed	-
		Planned	-	-	Planned	-
		Passed	-	-	Failed	-
		Passed	-	-	Passed	-
		Passed	-	-	Passed	-
		Failed	-	Passed	Failed	-

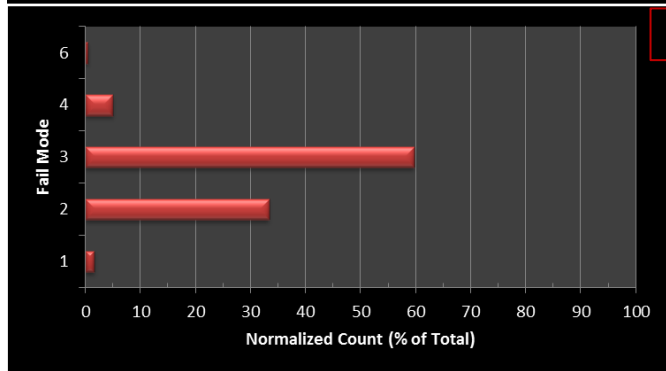
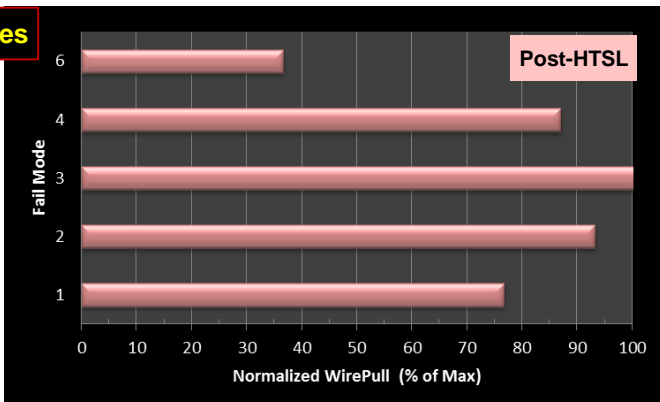
- Biased-HAST corrosion is prominent for certain mold-compounds, even if they are 'green'
- Autoclave can also show corrosion without bias.
- Failures do not correlate with residual Cl specs for the mold-compd.

# Wirepull: Exposure to Humidity or Temperature



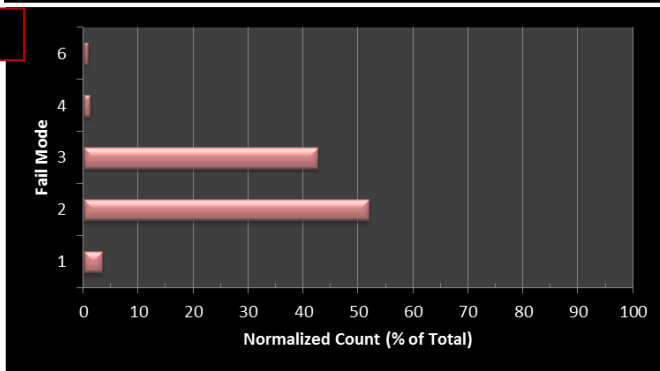
## Relative Strengths of Wirepull Fail-Modes

Mode1	Lifted ball
Mode2	Brk @ ball nck
Mode3	Brk @ mid-span
Mode4	Brk @ stitch heel
Mode5	Lifted stitch
Mode6	Lifted metal



## Occurrence Frequency of Fail-Modes

- Post-stress Peak WP is the same
- No lifted stitches observed
- **Lifted metal has low-strength**
- HTS and UHAST can highlight
- HTS can accelerate Lifted Ball





# What Have We Learnt?

## Looking Back

### Development and Qualification:

- √ *Development Process –*
  - √ *engaging the supply chain (engineering/fab/AT/suppliers)*
  - √ *Corner DOE's – making the bonds fails*
- √ *Reliability/Robustness by Design*
  - √ *Selecting Bill of Materials – mold-compounds, Chlorine, Au/Pd-Coated Cu, Roughened leadframes, capillaries*
  - √ *Bonding-Recipe Development – Process Technology, Device layout, bond-window*
  - √ *Reliability- Relationship to initial bond-strength*
  - √ *Package integrity – delamination in packages – bond-breaks, corrosion*
- √ *Enabling Techniques –*
  - √ *SEM x-sections of IMCs,*
  - √ *laser decapsulation,*
  - √ *Bond-pad IMC mapping,*
  - √ *Rapid in-line bond-inspection for over-bonding checks*
  - √ *Au- vs Cu-identification in encapsulated devices*
  - √ *TEM analysis techniques*

# What Have We Learnt?

## Looking Back

### Maintaining Quality & Reliability

- ✓ *Assembly process compatibility and integration (die-attach, plasma, trim-n-form, etc)*
- ✓ *Manufacturing Discipline - Bonder set-ups, bonder-to-bonder matching, handling & cleanliness, across-the-board assembly process controls, preventive maintenance*
- ✓ *Automation in assembly lines – recipe locks, change control*
- ✓ *Monitoring:*

SITE	PULLOUT DATE	LOT	COMPLIANCE PERIOD	RELCODE	RELB. STATUS	FINISH DATE	REVIEW DATE
MLA	2017-01-05	921000	1	MLAREL 9/ SN74VHC2 0/001	Completed	2017-02-17	2017-02-17
MLA	2017-01-10	703865	1	MLAREL 9/ SN74VHC2 0/001	Completed	2017-02-22	2017-02-22
MLA	2017-01-10	703979	1	MLAREL 9/ UCCE72010/001	Completed	2017-03-02	2017-03-02
MLA	2017-01-10	913333	1	MLAREL 9/ LMZ34002 0/001	Completed	2017-03-08	2017-03-08
MLA	2017-01-10	978674	1	MLAREL 9/ 2795000R 0/001	Completed	2017-02-24	2017-02-24
MLA	2017-01-10	7032027	1	MLAREL 9/ TPS84620 0/001	Completed	2017-03-08	2017-03-08
MLA	2017-01-14	923246	1	MLAREL 9/ CD405 BM 0/001	Completed	2017-02-17	2017-02-17
MLA	2017-01-05	978781	1	MLAREL 9/ CD74HC20 0/002	Completed	2017-02-17	2017-02-17
MLA	2017-01-08	922843	1	MLAREL 9/ ADS954E 0/001	Completed	2017-02-22	2017-02-22
MLA	2017-01-10	701997	1	MLAREL 9/ SN74VHC2 0/002	Completed	2017-02-22	2017-02-22
MLA	2017-01-02	979804	1	MLAREL 9/ 78220ATR 0/001	Completed	2017-02-27	2017-02-27
MLA	2017-01-03	979804	1	MLAREL 9/ TLC7528C 0/001	Completed	2017-02-22	2017-02-22

### Hunting out the pesky Cu-‘killers’:

*Manufacturing materials/environments (consumables, facilities, storage conditions, transportation, floor life, personnel etc)*

### Navigating to a better place

- *Get a handle on Chlorine*
- *Control Delamination in packages*
- *Identify better material solutions*
- *Decapsulation for wirepull analysis.*

# HiRel Concerns

# Critical Applications

- Critical Applications; Application-specific harsh environments
  - Avionics
  - Munitions
  - Missile Systems
  - Long term dormant storage
  - Extensive temperature cycling
  - High humidity
- Potential risks identified by the industry – not unique to HiRel
  - Bond integrity (Cu bonding to aluminum requires much tighter process controls and environments)<sup>1</sup>
  - Sporadic DPPM level corrosion due to mold compound interaction<sup>2</sup>
  - Bondwire breaks during temperature cycling (Higher CTE of Cu than Au, resulting in a higher failure rate in the presence of delamination)<sup>3</sup>
  - Corrosion at stitch-bonds due to moisture/solvent ingress in conjunction with delamination (not seen with Au wire)
- Commercial qualifications do not use sequential stresses. Additional application-level qualifications necessary

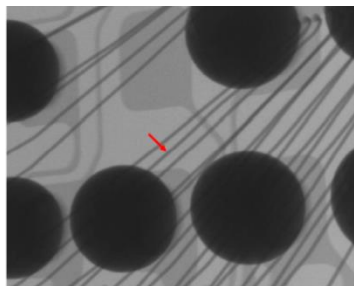
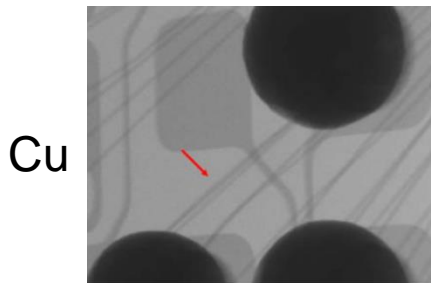
<sup>1</sup> Luke England and Tom Jiang. "Reliability of Cu Wire Bonding to Al Metallization". Electronic Components and Technology Conference. 2007.

<sup>2</sup> Hui Teng, et al. "Effect of Moisture and Temperature on Al-Cu Interfacial Strength". International Conference on Electronic Packaging Technology & High Density Packaging, 2008.

<sup>3</sup> Bart Vandevelde and Geert Willems. "Early fatigue failures in Cooper wire bonds inside packages with low CTE Green Mold Compounds". 4<sup>th</sup> ESTC Conference. 2012, Amsterdam, The Netherlands. 28

# Defense OEM Concern

- COTS copper bondwire identification
  - Mixed copper and gold bondwire devices in end system prior to customer qualification
  - A simple method to identify the wire-type, base on Atomic number differences between Au and Cu: X-Ray



# Summary

- Cu-wirebond is
  - intrinsically capable of high reliability in plastic packages
  - sensitive to several external factors and environments
  - in production for several years in a variety of commercial & Industrial applications
- Key care-about for reliability in commercial applications are
  - Bond integrity
  - Sporadic DPPM level corrosion
  - Corrosion and bond-cracks when package-integrity is compromised

# Summary

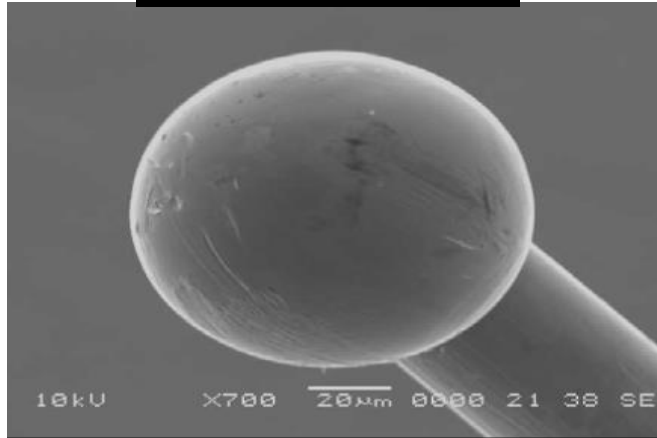
- Cu-wirebond requires attention to the following key areas
  - Design/Structure of Bond-pads on the die
  - Selection of Package Materials
  - Design & Control of Assembly Processes (e.g. DOE, die-attach, mold, trim-form etc)
  - A new mindset on the factory floor, and manufacturing discipline
  - Seamless collaboration between Device-manufacturer, Assembly/Test and their suppliers

# Back Up

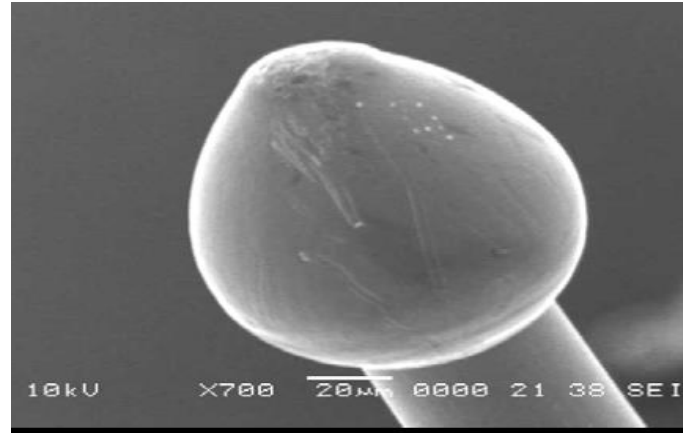


# Free-Air Ball Formation

Desired FAB shape



- Oxidation of Cu during EFO leads to distorted ball during cool-down.

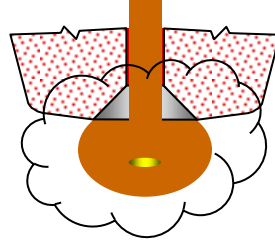


Distorted FAB

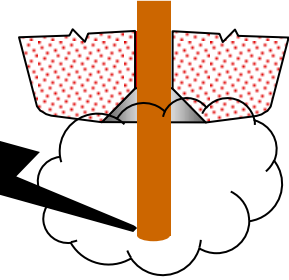
- Oxidized ball presents bonding challenges – NSOP or pad-damage.

# Copper Wire Bond Process

## 3. Free Ball Formation



1. Wire feeds into capillary from spool



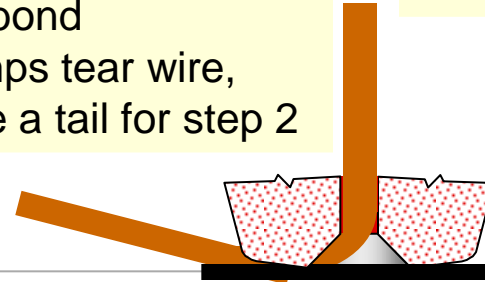
2. EFO Spark



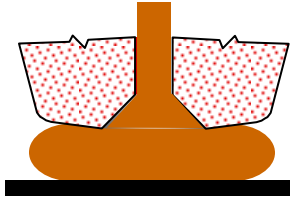
Forming Gas  
95% N<sub>2</sub>/5% H<sub>2</sub>



6. 2nd bond  
7. Clamps tear wire,  
leave a tail for step 2



4. 1st Bond:  
Force, USG, Heat, Time



5. Wire looping to lead finger

